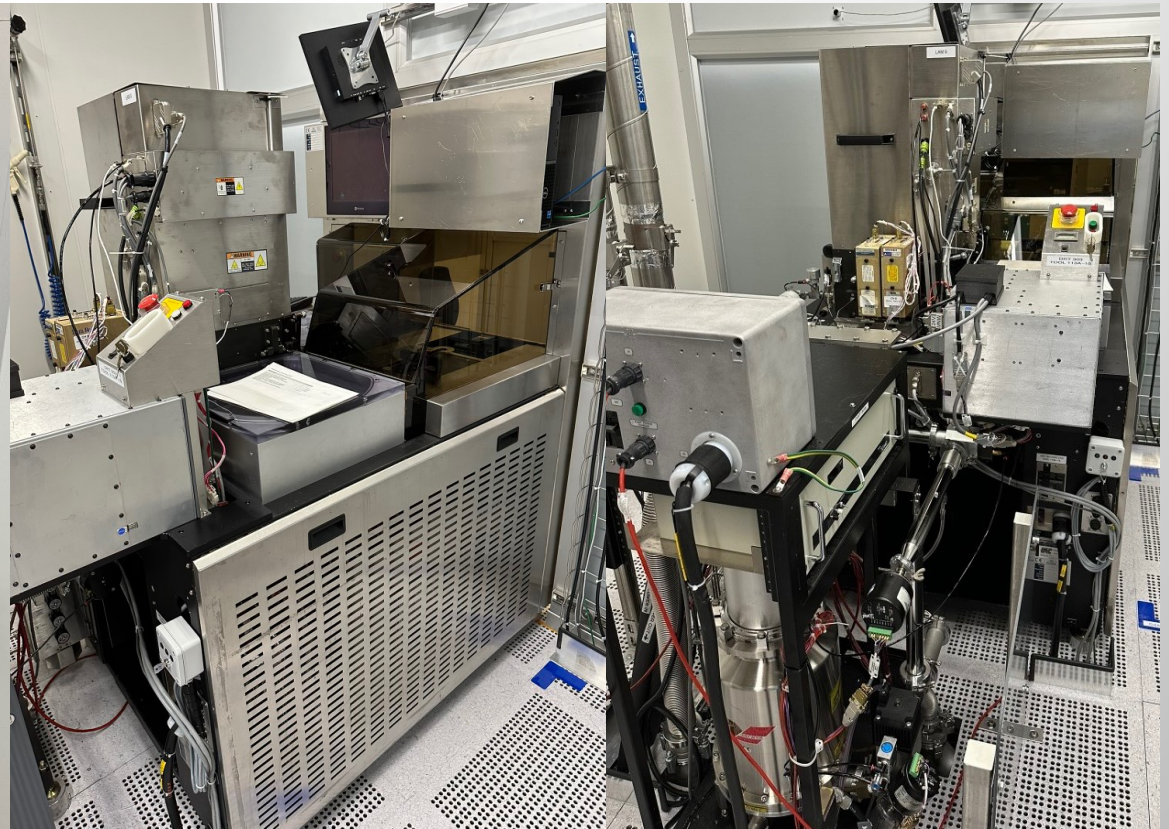


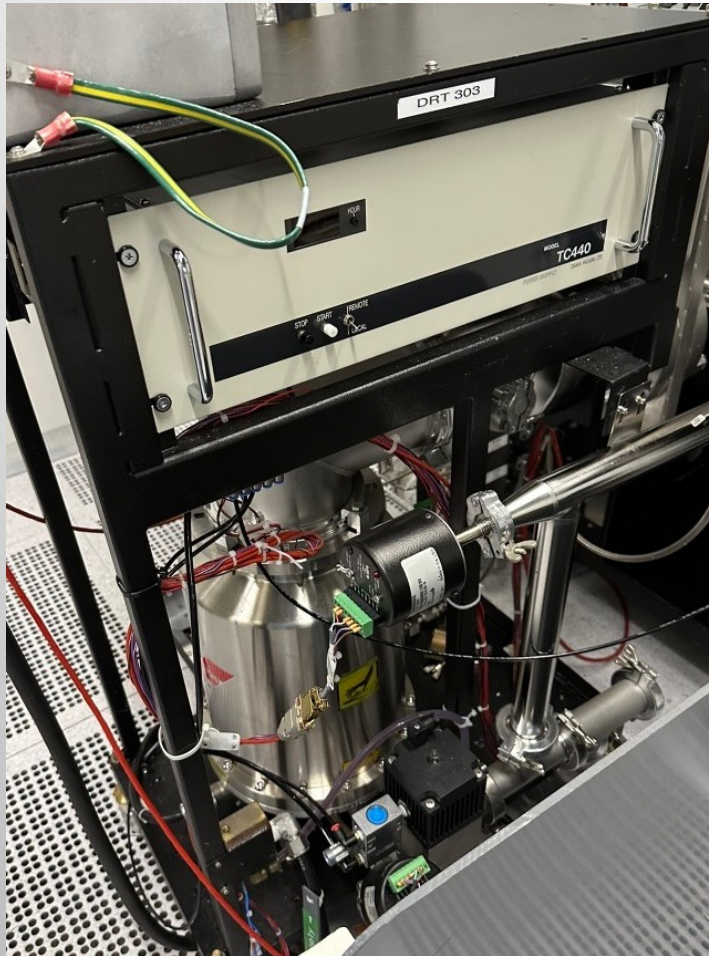


LAM Research
4520XL Oxide Etch 150mm Configuration
SN 2986

**LAM Research
4520XL Oxide Etch SN 2986**



LAM Research 4520XL Oxide Etch SN 2986



LAM Research 4520XL Oxide Etch SN 2986



Tool Model : 4520XL
Tool Serial Number : 2986
Bulkhead system mount w/tunnel covers
Dual monitor upgrade
Hine 38A open cassette Send/Receive indexers
Software Version: Envision
Oxide etcher, 6"
Clamp type, ESC
RF power Rack 2x ENI Gemini RF Generator
Chiller Unit LAM 2080
AC Rack AC Power Distribution
Moving gap
Back Helium Cooling
Main Power 208V, 3 Phase, 5Wire, 175A, 60/
Belt driven load station
Standard load station shuttle spatula
Upper chamber gap drive encoder
Aluminum upper chamber electrode

Single lower chamber endpoint detector (405/520nm) Non-
-heated endpoint window
HGP Pump/Controller and VAT 65 ISO Valve
AC--2 chamber pressure control
Lower chamber RGA port
8 -- Gas box Orbital gas box
Gas 1: AR 500sccm
Gas 2: CF4 20 sccm
Gas 3: CHF3 20 sccm
Gas 4: CHF8 20 sccm
Gas 5: CO 200 sccm
Gas 6: O2 low 20 sccm
Gas 7 O2 High 1000 sccm
Gas 8: N2 100sccm
UPC: He (50 sccm)
AC input box for AC power inlet
Trip breakers AC/DC power box

Solutions on Silicon BV

Your service partner for LAM Research Equipment

- **Equipment Support**
PM, CM, Trouble shooting, Upgrading, Training and Onsite Service Contracts
- **Process Support**
Process design, Improvement, Fab-to-Fab Transfer and Integration
- **Refurbishment**
From custom to complete refurbishment
- **Relocation**
Auditing, Fingerprinting, Decommissioning, Installation, Acceptance
- **Materials**
Supplier of first class second source materials

